

FORM PT01449
(REV. 8-83)

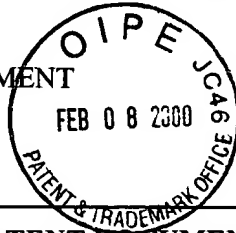
U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

ATTY. DOCKET NO.
TNCR.170US1

SERIAL NO.
09/405,716

INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)



APPLICANT
HAIMING WANG ET AL.

FILED
September 24, 1999

GROUP
2878

U. S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE
38	4 0 5 3 2 3 2	10/11/7	Dill et al.			
38	4 3 0 6 8 0 9	12/22/8	Azzam			
38	5 0 1 8 8 6 3	5/28/91	Vareille et al.			
38	5 0 4 2 9 5 1	8/27/91	Gold et al.			
	5 1 6 6 7 5 2	11/24/9	Spanier et al.			
	5 1 8 1 0 8 0	1/19/93	Fantom et al.			
	5 4 1 6 5 8 8	5/16/95	Ducharme et al.			
	5 4 8 6 7 0 1	1/23/96	Norton et al.			
	5 5 9 6 4 0 6	1/21/97	Rosencwaig et al.			
	5 6 0 8 5 2 6	3/4/97	Piwonka-Corle et al.			
	5 7 4 7 8 1 3	5/5/98	Norton et al.			
38	5 8 5 9 4 2 4	1/12/99	Norton et al.			

FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANS.? (YES/NO)
WO 99 0 2 9 7 0	1/21/99	International			N/A

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent pages, Etc.)

38	✓	"Analysis of Semiconductor Surfaces With Very Thin Native Oxide Layers By Combined Immersion And Multiple Angle Of Incidence Ellipsometry," I. Ohlidal et al., <i>Applied Surface Science</i> , 35 (1988-89) pp. 259-273
	✓	"Determination Of The "Optical" Thickness And Of The Filling Factor Of Discontinuous Au Films From Photometric And Ellipsometric Measurements," E. Elizalde eta l., <i>Optics Communications</i> , Vol. 60, No. 6, December 15, 1986, pp. 378-382
	✓	"Variable Angle Spectroscopic Ellipsometry," S.A. Alterovitz et al., <i>Solid State Technology</i> , March 1988
	✓	"Application of spectroscopic ellipsometry to complex samples," J. L. Freeouf, <i>Appl. Phys. Lett.</i> , 53(24), December 12, 1988, pp. 2426-2428
38	✓	"Spectroscopic ellipsometry Studies of SIMOX structures and correlation with cross-section TEM," <i>Vacuum</i> , Vol. 42, Nos. 5/6, 1991, pp. 359-365

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38

DATE CONSIDERED

5/2/02

* EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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28	5 8 7 2 6 3 0	2/16/99	Johs et al.			
28	5 8 7 7 8 5 9	3/2/99	Aspnes et al.			

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DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANS.? (YES/NO)

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28	✓	"Spectroscopic Ellipsometry for the Characterization of Thin Films," F. Ferrieu et al., <i>J. Electrochem. Soc.</i> , Vol. 137, No. 7, July 1990, pp. 2203-2208
	-	"Rotating-compensator multichannel ellipsometry for characterization of the evolution of nonuniformities in diamond thin-film growth," J. Lee et al., <i>Applied Physics Letters</i> , Vol. 72, No. 8, February 23, 1998, pp. 900-902
	-	"Broadband spectral operation of a rotating-compensator ellipsometer," J. Opsal et al., <i>Thin Solid Films</i> , 313-314 (1998), pp. 58-61
28	-	"A Self-Calibrating Modulation Ellipsometer," S. Ducharme et al., <i>SPIE</i> , Vol. 2839, pp. 373-384

EXAMINER

Zalaw. S. J. K.

DATE CONSIDERED

5/2/02

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PATENT DOCUMENT
 OCT 03 2000
 JCS63700

U.S. Department of Commerce, Patent and Trademark Office					Atty Docket No.		Serial No.	
					M-10684-2P US.		09/405,716	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Applicant(s)			
(Use several sheets if necessary)					Haiming Wang, et al.			
					Filing Date		Group	
					September 24, 1999		2878	

U.S. Patent Documents							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
28	AA	5,687,721	11/18/97	Kuhls			
38	AB	5,956,148	09/21/99	Celii			
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
70	AQ✓	Written Opinion dated March 13, 2001
	AR	
	AS	

Examiner <i>Zakaria-Sa</i>	Date Considered <i>8/2/02</i>
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Applicant(s)			
(Use several sheets if necessary)				HAIMING WANG ET AL.			
				Filing Date		Group	
				September 24, 1999		2878	
U.S. Patent Documents							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
38	AA	4,893,932	1/16/90	Knollenberg			
	AB						
	AC						
	AD						
	AE						
	AF						
	AC						
	AH						
	AI						
Foreign Patent Documents							
							Translation
		Document	Date	Country	Class	Subclass	Yes No
35	BJ	WO 00/47961	8/17/2000	International			
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
38	CK	International Search Report mailed 10/27/2000					
	CL	"Design of a scanning ellipsometer by synchronous rotation of the polarizer and analyzer," Liang-Yao Chen et al., <i>Applied Optics</i> , Vol. 33, No. 7, March 1, 1994, pp. 1299-1305					
	CM	"A Simple Fourier Photopolarimeter with Rotating Polarizer and Analyzer for Measuring Jones and Mueller Matrices," R.M.A. Azzam, <i>Optics Communications</i> , Vol. 25, No. 2, May 1978, pp. 137-140					
	CN	"The Influence of Cell Window Imperfections on the Calibration and Measured Data of Two Types of Rotating-Analyzer Ellipsometers," A. Straaijer et al., <i>Surface Science</i> 96, 1980, pp. 217-231					
35	CO	"Automatic rotating element ellipsometers: Calibration, operation, and real-time applications," R.W. Collins, <i>Rev. Sci. Instrum.</i> Vol. 61, No. 8, August 1990, pp. 2029-2062					
Examiner		Date Considered		5/2/02			
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